

2.5D & 3D Packaging Cost Model

Which applications are right for this technology?

This is the first cost model to cover the **total cost and yield from fabrication of the wafer to complete assembly**, for both 2.5D and 3D applications. Many detailed parameters are available for editing, but only a few inputs are required to run the analysis. For parameters you choose not to edit yourself, complex SavanSys algorithms automatically assign default values based on your other entries and extensive, up-to-date industry knowledge.

Use the model to:

- Compare the cost of 2.5D and 3D packaging to see what makes sense for your product.
- Include supplier specific details and incoming die preparation in your analysis.
- View the detailed costs—including labor, material, capital, tooling, and yield impacts—for every step.

Sample parameter list:

Design

2.5D process flow (chip-on-chip/wafer/substrate)
Number of Die
Interposer size
Number of RDL
TSV Aspect Ratio
Number of TSV per Die

Preparation of Die

Incoming Wafer Cost
Location/Labor Rate
Die Size

Supplier Settings

Labor rate
Lot size
Overhead rate
Margin/Risk factor
Factory utilization

Advanced

TSV formation process type
TSV formation yield
RDL creation process type
Underfill process
....and more

This model is the result of a joint project between TechSearch International, Inc., the leading market research firm in semiconductor packaging and assembly trends, and SavanSys Solutions LLC, the leader in electronic manufacturing cost modeling.



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TECHNOLOGY TRADE-OFFS WHAT'S THE COST IMPACT OF:

- Additional RDL layers?
- Higher costs, better yield?
- Increasing TSV Count?
- Interposer versus true 3D?

COST BREAKDOWN SUMMARIZE TOTAL COST

- Results are broken down into FEOL, BEOL, TSV creation and assembly.
- Wafer cost and unit cost are presented separately.
- Risk and yield are included in the total cost.

PROCESS DETAILS COMPLETELY CUSTOMIZABLE

- Disable specific process steps.
- Account for test activities.
- Customize process steps with known data (equipment cost, throughput, material, and more).

SUPPLIER SPECIFICS

An optional enhancement is to create a model calibrated to your particular technology or to a specific supplier (internal or external). Ask us for more details.

Design Options			Results		
Configuration	Interposer	Interposer	Total Package Cost	Current	Previous Run
Integration	Chip-on-Chip	Chip-on-Chip	Die To Interposer Ass	\$0.000	\$0.000
# of Die	2	2	Interposer to Substrat	\$0.000	\$0.000
Package Size	21x21	27 x 27	Integration Costs etc...	\$0.000	\$0.000
Interposer			Interposer Yield	0.00%	0.00%
Interposer Size	12x12	12 x 12	Package Yield	0.00%	0.00%
# Interposer to Die RDL	1	1			
# Interposer to Substrate RDL	1	1			
TSV					
# TSV Per Die	100	100			
TSV Diameter (um)	10.00	10.00			
TSV Depth (um)	90.00	90.00			
TSV Aspect Ratio (calcula	9.00				

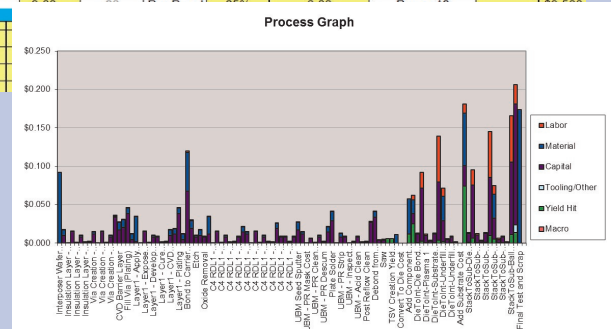
Enter values (or let SavanSys select default values) on the main page to construct the initial process.

Supplier Settings	Fab 1
Labor Rate	Taiwan
Factory Utilization	85%
Lot Size / Batch Size (# Wafe	12.00
Overhead/Indirect %	110.00%
Margin/Risk Factor %	40.00%

After constructing and running the process based on your initial inputs, view/edit the details of every processing step.

Step Name	Enabled?	Time (min)	Through put (UPH)	Time Units	Operator Utilization	Defect Density or PPM	Defect Density Units	Step Yield	Equipm Cos
[01] Interposer Wafer Cost	YES	0.00		Per Panel	25%	0.00	Per cm²		\$0
[11] Insulation Layer - CVD	YES	2.00	30	Per Panel	25%	0.00	Per cm²		\$2,500
[11] Insulation Layer - Mask Cost	YES	0.00		Per Lot	25%	0.00	Per cm²		\$0
[11] Insulation Layer - Expose	YES	2.00	30	Per Panel	25%	0.00	Per cm²		\$4,000
[11] Insulation Layer - Clean Mask	YES	5.00	12	Per Lot	100%	0.00	Per cm²		\$1,000
[11] Insulation Layer - Etch	YES	20.00	3	Per Lot	25%	0.00	Per cm²		\$2,500
[11] Insulation Layer - Cure	YES	90.00	1	Per Lot	25%	0.00	Per cm²		\$100,000
[11] Insulation Layer - Descum	YES	1.00	60	Per Panel	25%	0.00	Per cm²		\$750,000
[11] Via Creation - Photoresist	YES	2.50	24	Per Panel	25%	0.00	Per cm²		\$2,500
[11] Via Creation - Mask Cost	YES	0.00		Per Lot	25%	0.00	Per cm²		\$0
[11] Via Creation - Expose	YES	2.00	30	Per Panel	25%	0.00	Per cm²		\$4,000
[11] Via Creation - Clean Mask	YES	5.00	12	Per Lot	100%	0.00	Per cm²		\$1,000
[11] Via Creation - Develop	YES	20.00	3	Per Lot	25%	0.00	Per cm²		\$2,500
[11] Deep Reactive Ion Etch	YES	5.00	12	Per Panel	50%	0.00	Per cm²		\$3,500
[11] CVD Barrier Layer	YES	2.50	24	Per Panel	25%	0.00	Per cm²		\$3,500
[11] PVD Cu Seed Layer	YES								
[11] Fill Via (Plating)	YES								
[11] CMP	YES								
[12] Layer1 - Apply Dielectric	YES								
[12] Layer1 - Mask Cost (Trench)	YES								
[12] Layer1 - Expose (Trench)	YES								

Results are presented as a summary on one page, and also as a detailed graph (shown here).



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_____	_____
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Price per model (annual corporate license): \$12,500.00

☐ I want to purchase the 2.5D & 3D Packaging Cost Model

Purchase order number: _____

AMEX, VISA, MC, JCB: _____

Total amount: _____

Exp: _____